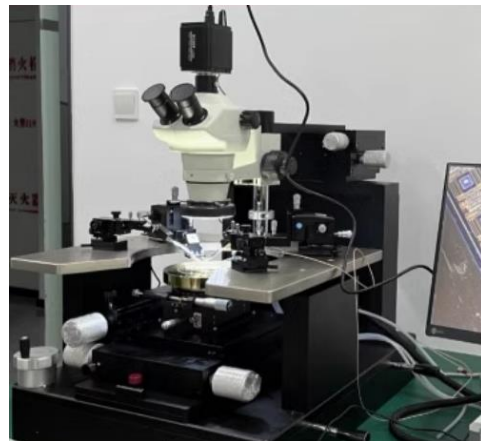


# High Frequency Probe Station

## Introduction

The high frequency probe station is a highly-precise manual probe platform for wafers and substrates up to 150 mm. It is ideal station for a wide range of applications, such as RF and mm-Wave characterization, device and wafer test, fault analysis, MEMS and optoelectronic tests. The modular design provides a flexible configuration for various of applications. It can be integrated with third part instrumentation, minimizing the setup times and improving measurement performance.



## Technical Specification

Standard Wafer Chuck Diameter: 150 mm

Chuck Stage Travel Range: 155 mm × 155 mm

DUT Size Supported: Wafers 25 mm to 150 mm or Shards

Vacuum Ring Diameter: 22 mm, 42 mm, 66 mm, 88 mm, 110 mm

Surface Planarity:  $< \pm 3 \mu\text{m}$

Chuck Stage Resolution: 5  $\mu\text{m}$

Z Height Adjustment Range: 10 mm

Chuck Stage Theta Travel Range: 0~360°